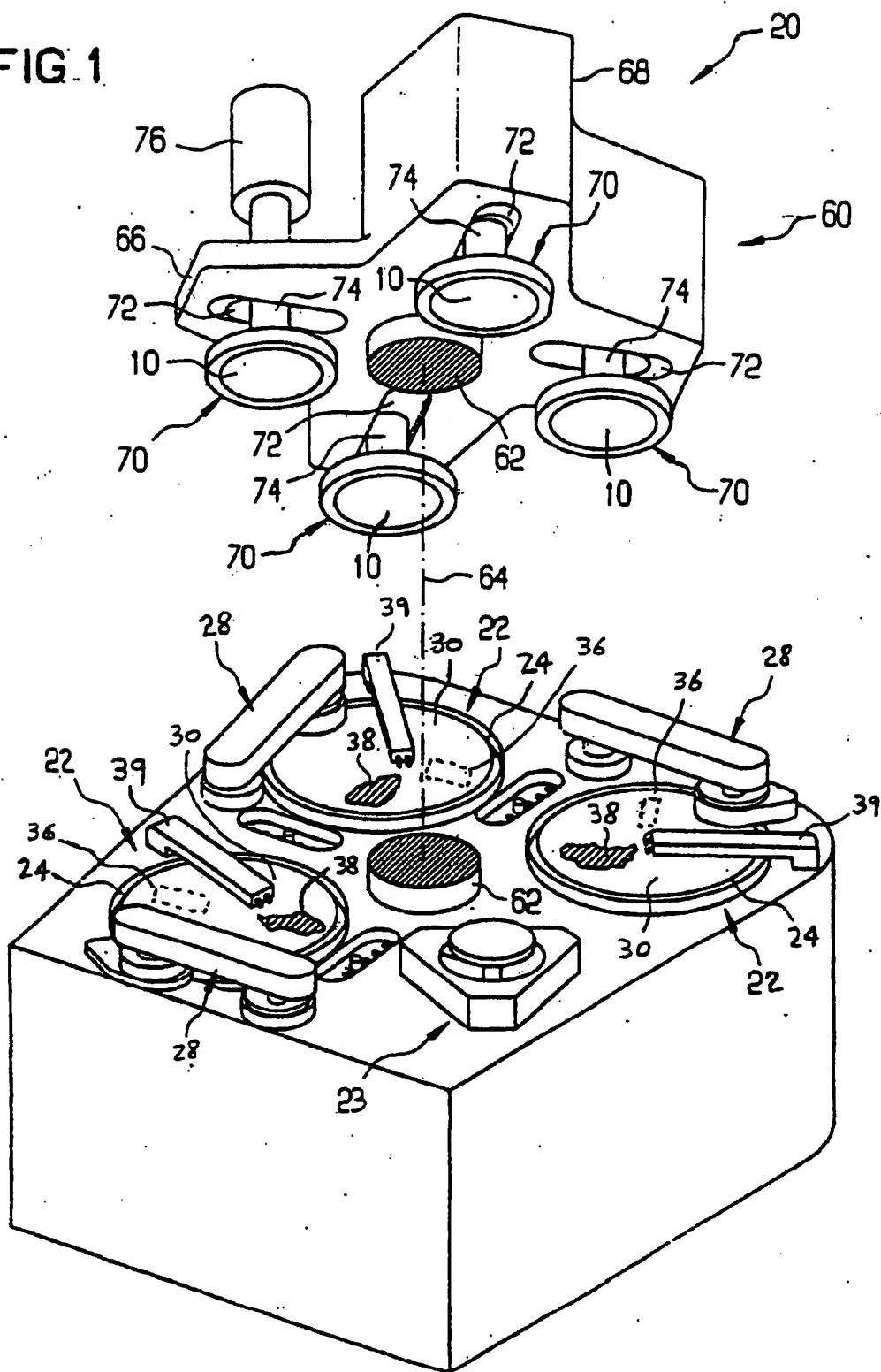
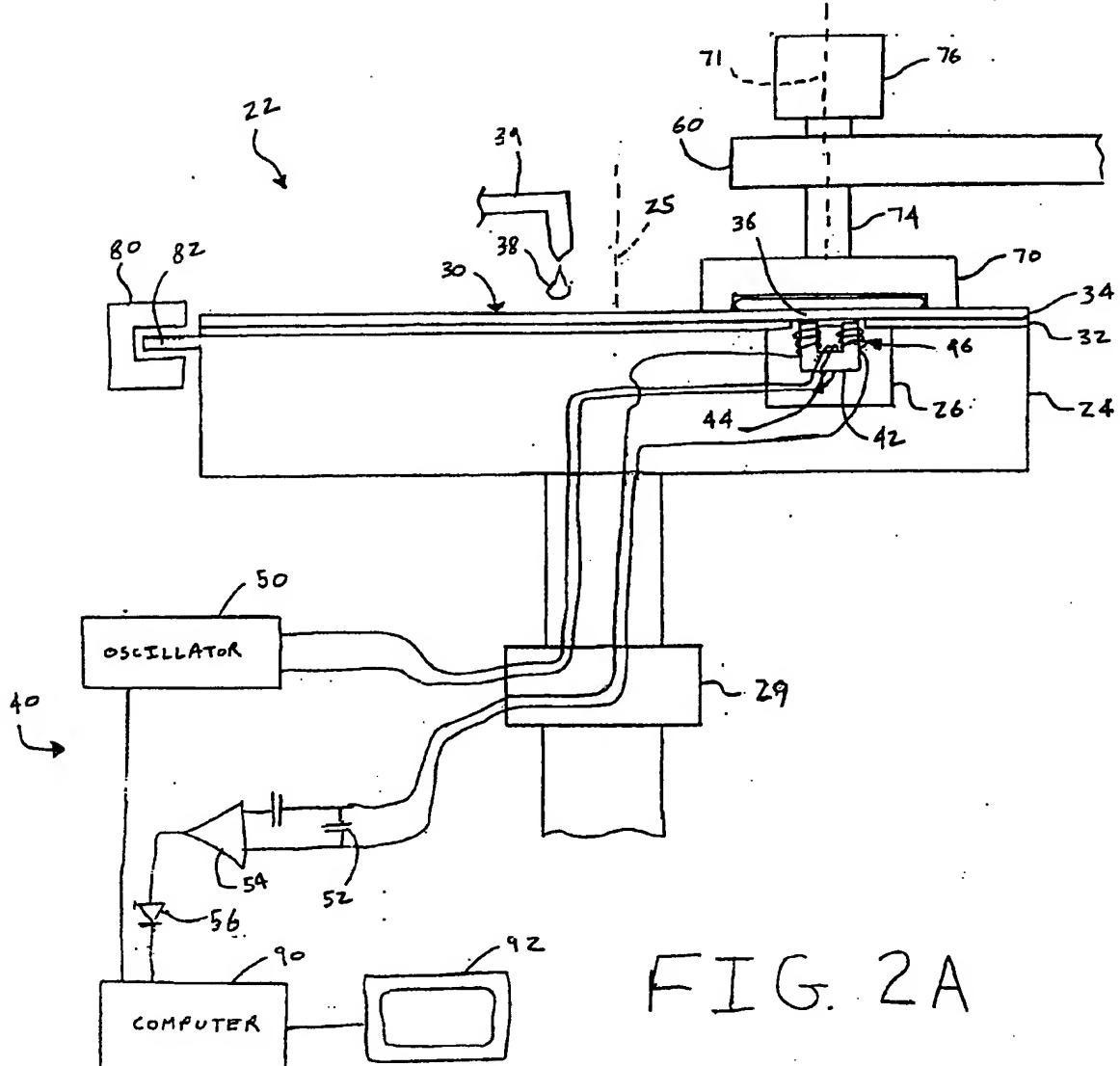


FIG. 1





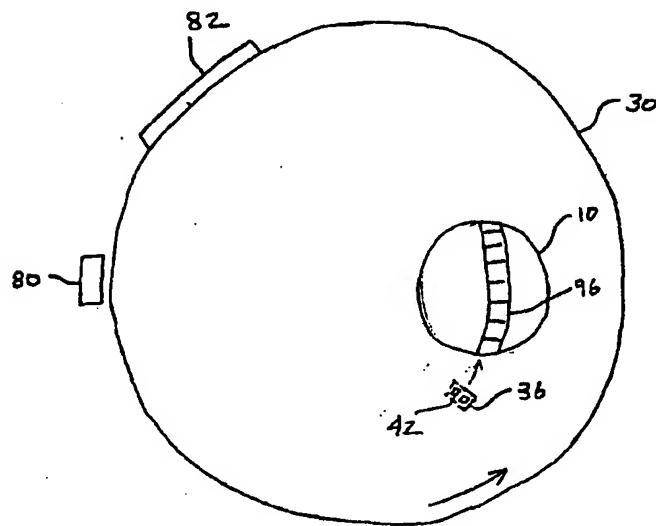


FIG. 2B

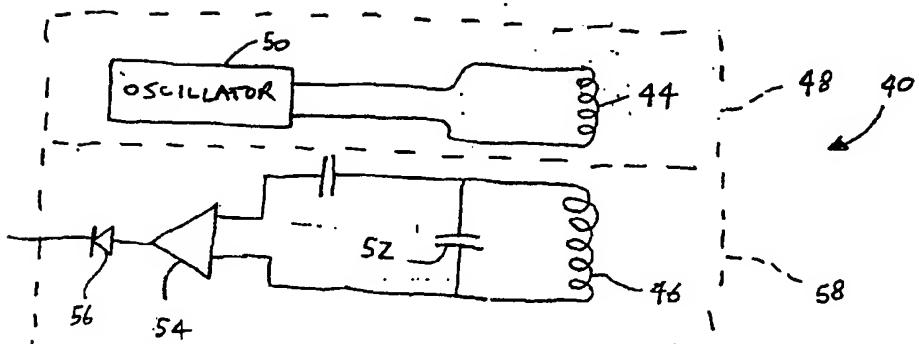


FIG. 3

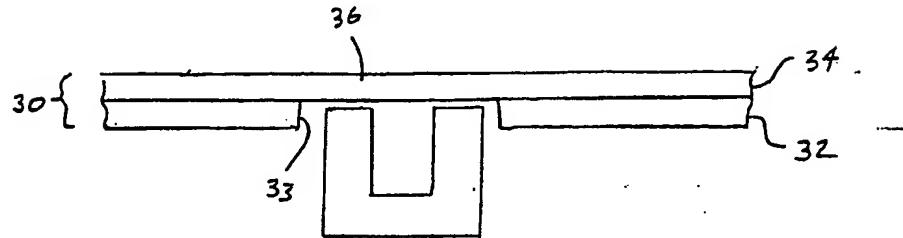


FIG. 4A

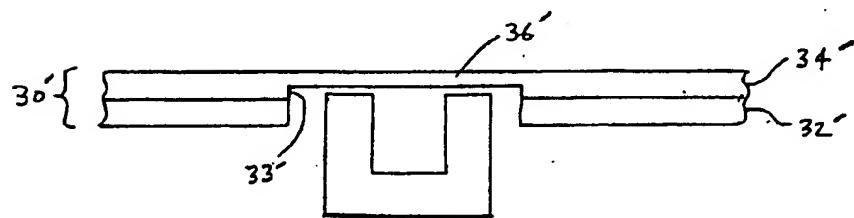


FIG. 4B

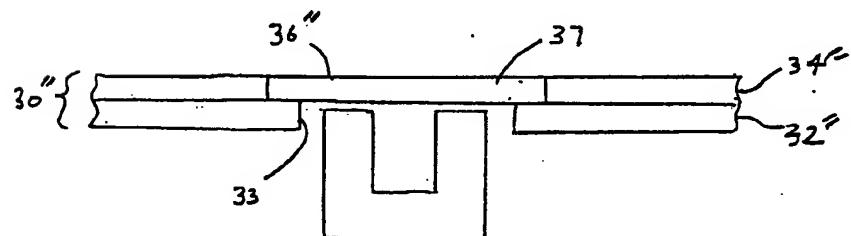


FIG. 4C

Applicants: Doyle E. Bennett et al.

Applicant: BOYCE E. BOYCE  
**CHEMICAL MECHANICAL POLISHING APPARATUS WITH  
NON-CONDUCTIVE ELEMENTS**

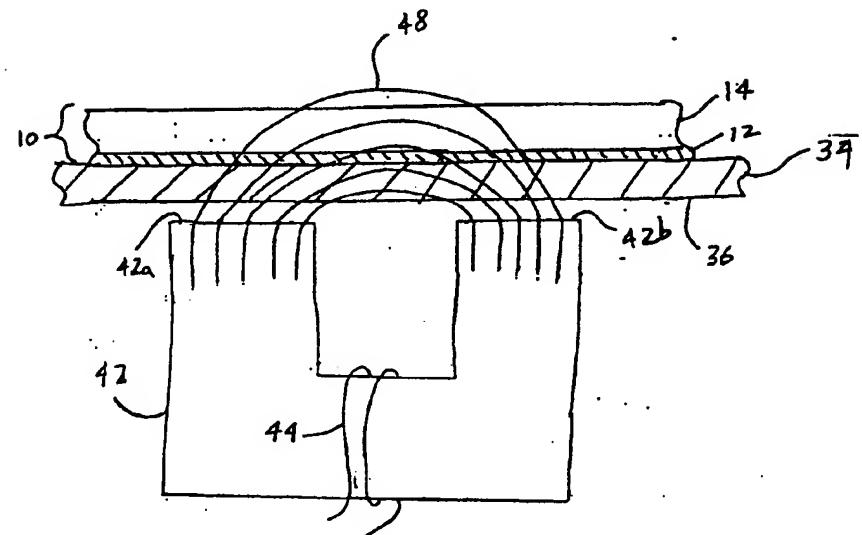


FIG. 5

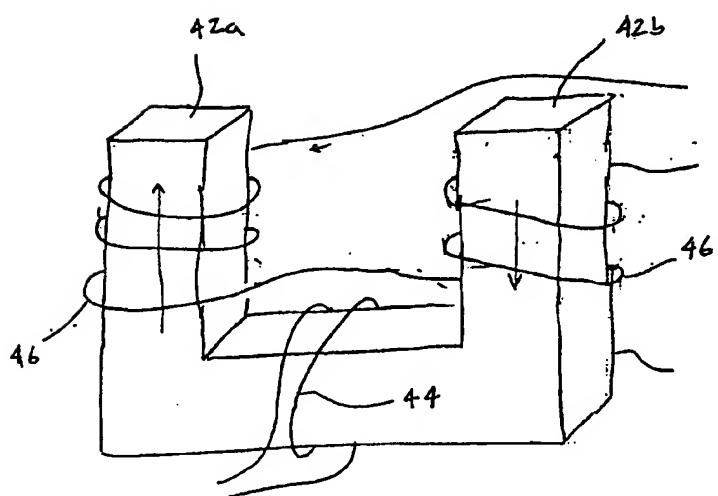


FIG. 6

Applicants: Doyle E. Bennett et al.

CHEMICAL MECHANICAL POLISHING APPARATUS WITH  
NON-CONDUCTIVE ELEMENTS

FIG. 7A

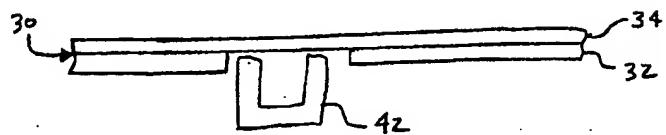


FIG. 7B

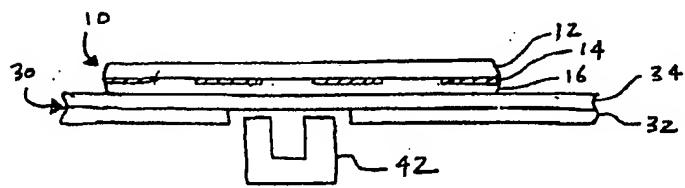


FIG. 7C

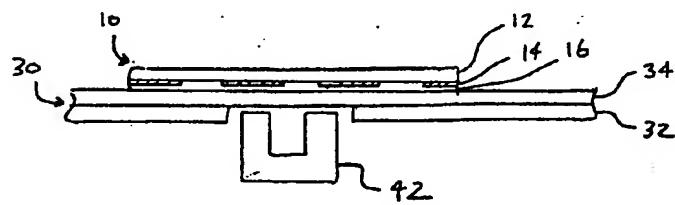
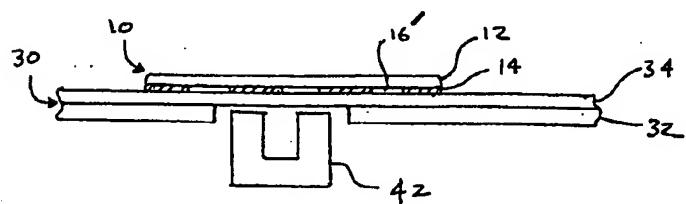


FIG. 7D



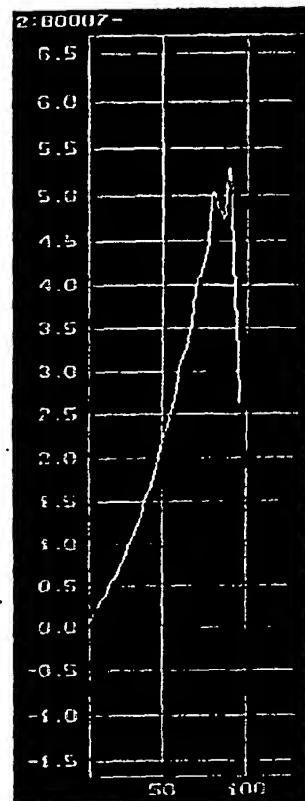
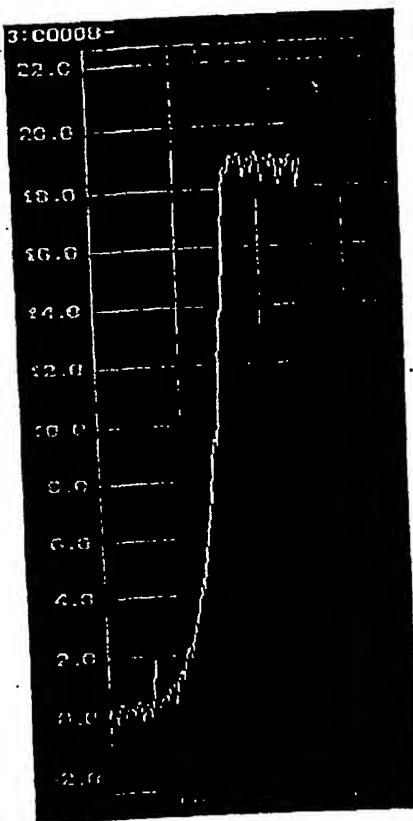


FIG. 8

FIG. 11

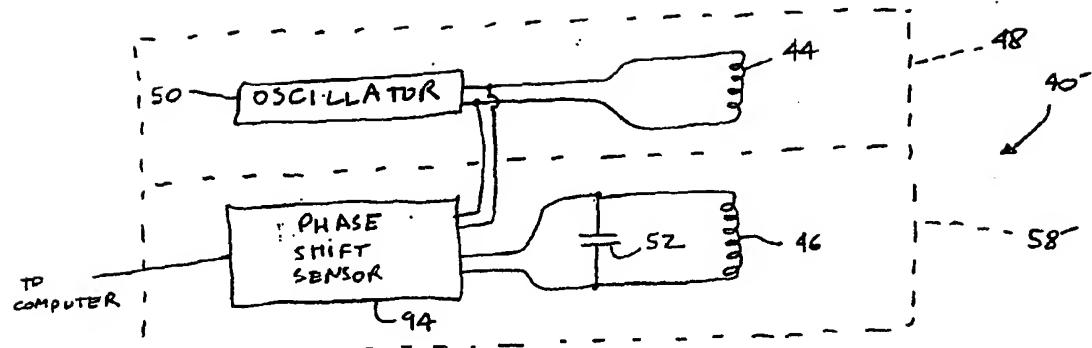
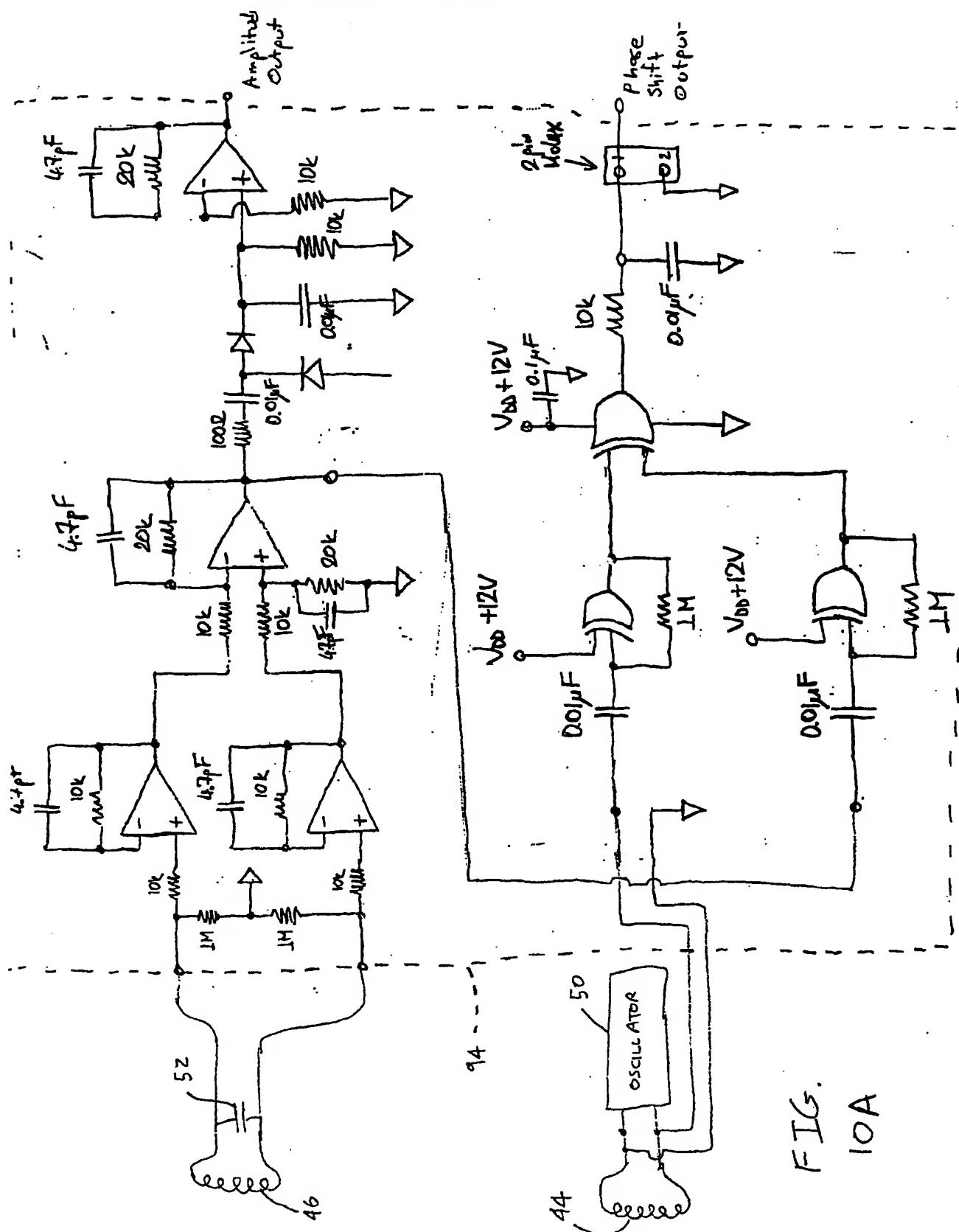


FIG. 9



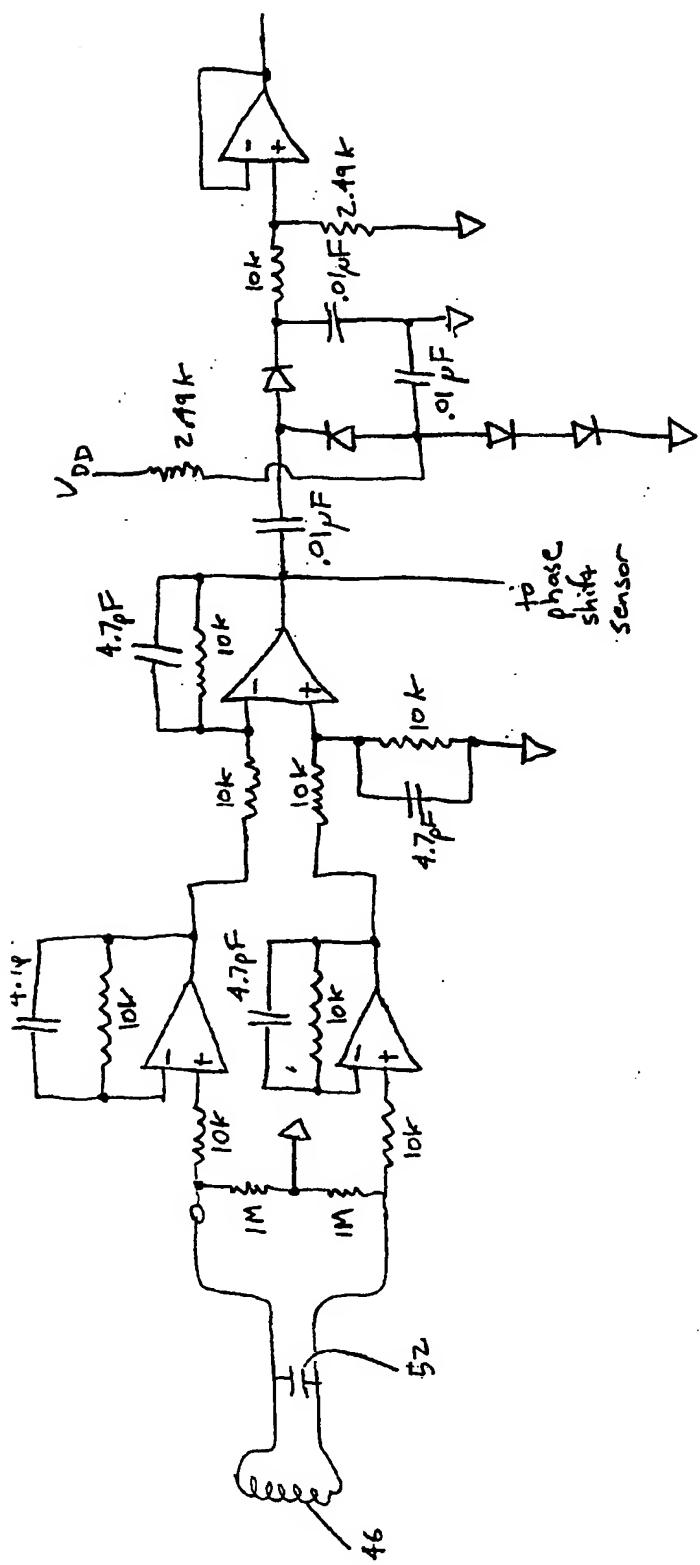


FIG. 10 B

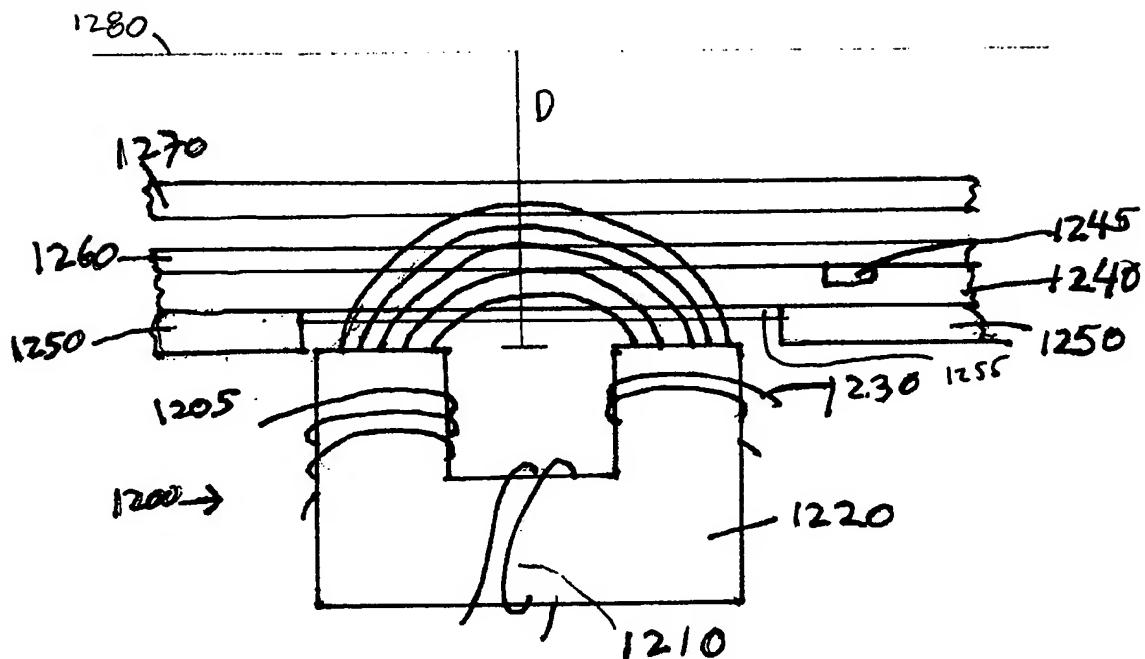


FIG 12

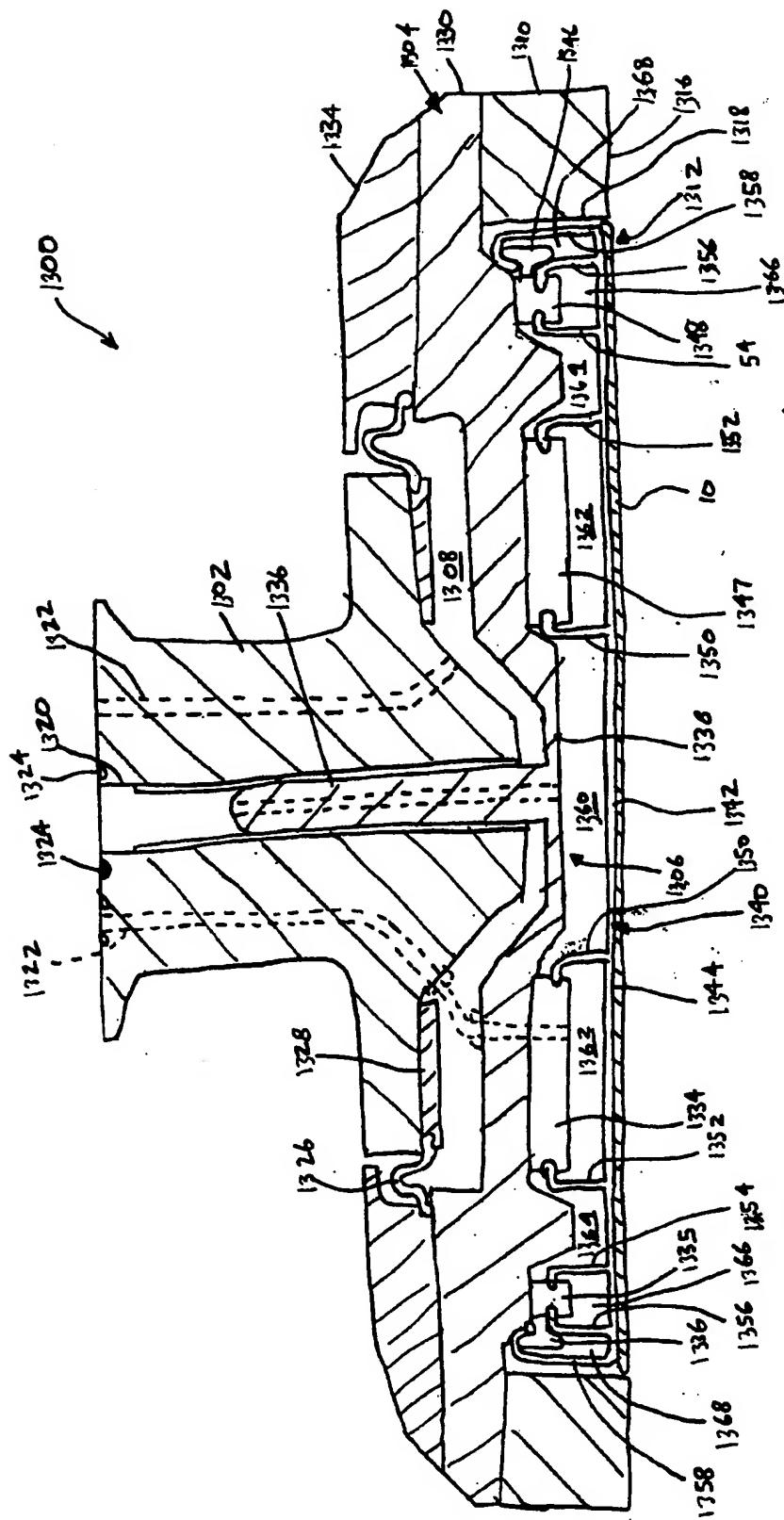


FIG. 13

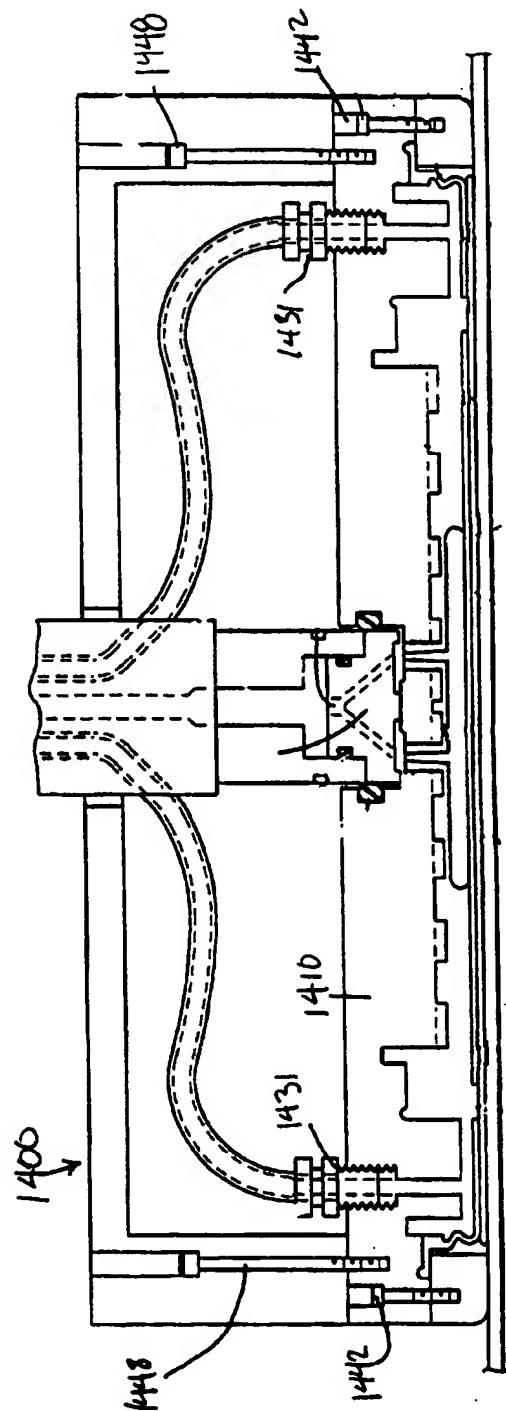
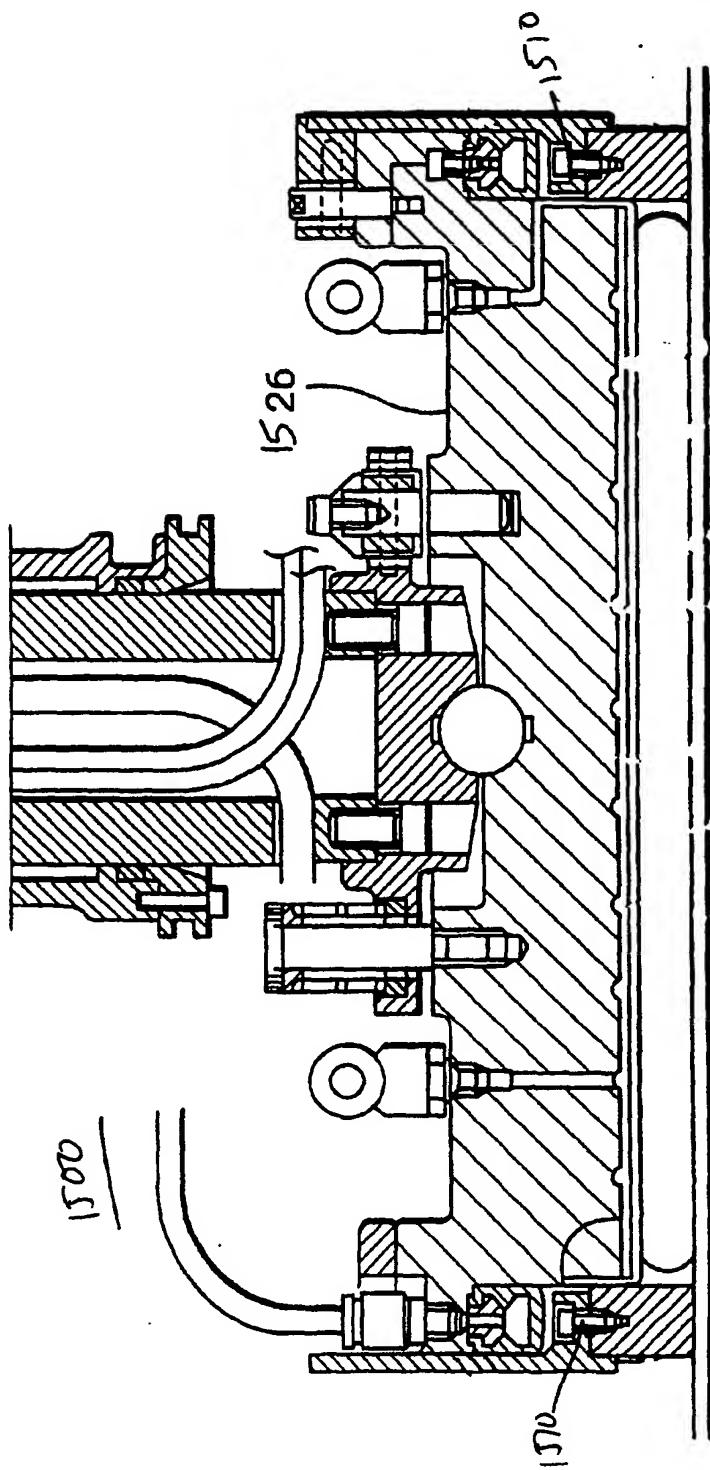


FIG. 14

*Fig. 15*

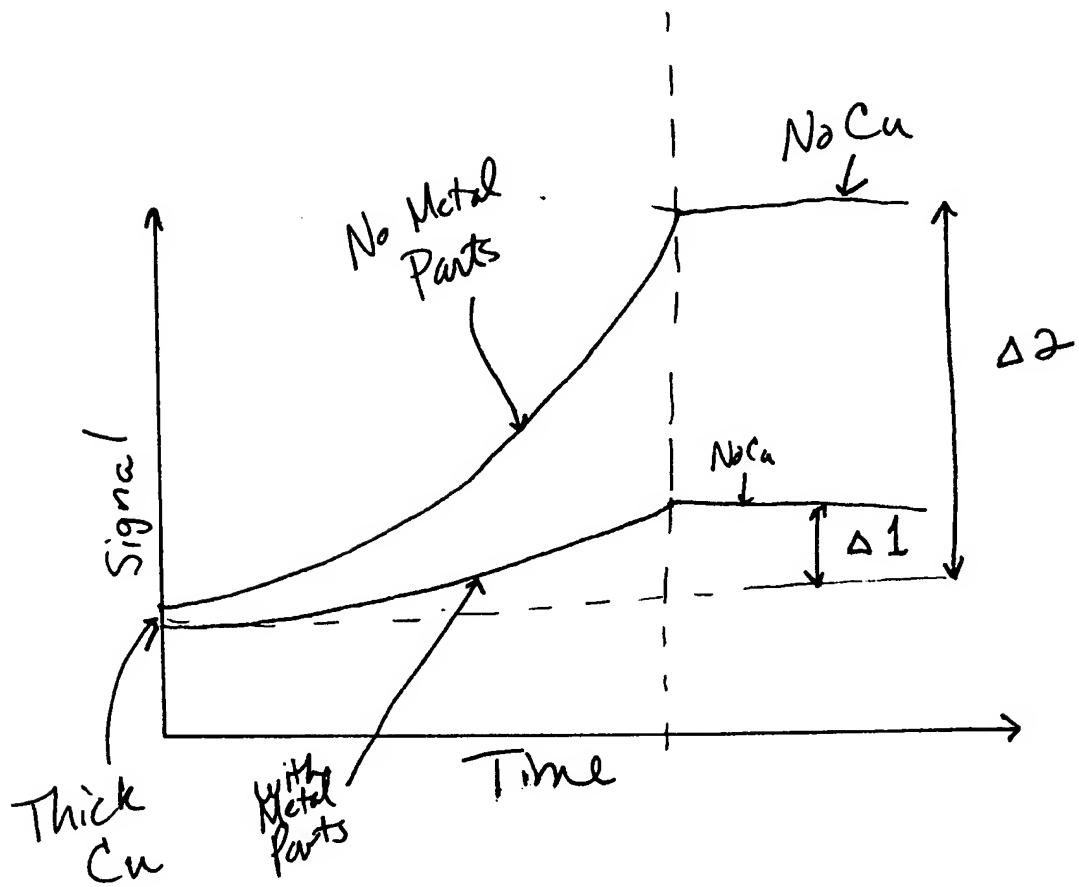


FIG. 16